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2 www.esealink.com

Sealink Products



Specifications

Motion	Rotary, Linear, Rotary & Linear, Co-Axial, Multi-Axial		
Media	Reactive Gas, Inert Gas, Water, Oil and other Liquids		
Temperature Range	$-20 \sim 150$ °C (-4 $\sim +300$ °F) without cooling system		
	-20 ~ 400°C (-4 ~ +750°F) with optional cooling system		
Leakage Rate in Vacuum	Up to 7.5 x 10 19 Pa-m 1/s by Helium Leakage Detector		
Leakage Rate in Pressure	Up to 3.5 x 10 ² bar/min, 0.5 psi/min by Nitrogen gas		
Vacuum	Max. 10 * Torr, Max. 10 6 Pa		
Pressure	Max. 50 bar (PV Limits: Max. 50)		
Speed	Max. 15 m/s		
Shaft Diameter	ø6 ~ ø1,800 mm		
Torque	Depending on the type and customer's application requirement		

Sealink also provides customized products to meet the operating conditions of your devices.

Comparison of Three Types of Sealing Units

Seal Type	Mechanical Seal	Magnetic Seal	Sealink Seal
Theory	Face Contact	Ferrofluid	Nonlinear Contact
Vacuum	Х	0	0
Pressure	0	Х	0
Gas	X	0	0
Liquid	0	Х	0
Lubricant	Required	Not Required	Not Required

All our products are hermetically sealed by our unique sealing technology and operated in dry running condition without buffer fluid reservoir for the lubricants and cooling systems below 150°C/300°F (operable up to 400°C/750°F with optional cooling systems).

And our linear sealing systems do NOT use metallic bellows which result in saving space and cost.

We have PATENTS!



Petrochemical, Fine Chemical, Marine, Steel and General Machinery Industries

Mixer, Agitator, Reactor Vessel, Stirrer, Crystallizer, Excavators, Dissolving tank, Stern tube, Turbines, Coil Processing Mandrels, Drier etc.

Semiconductor Equipment, LCD and OLED Industries

CVD, MOCVD, LPCVD, PECVD, PCD, ALD, CMP, OLED, LCD device, FPD device, Wafer handling device, Vacuum deposition system, Ion Implanter, Etcher, Asher, Edge Grinder, Scrubber, RTP, Sputter, Lampdevice, Autoclave, Wafer robot, etc.



